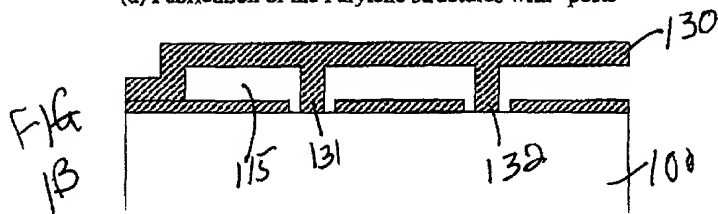
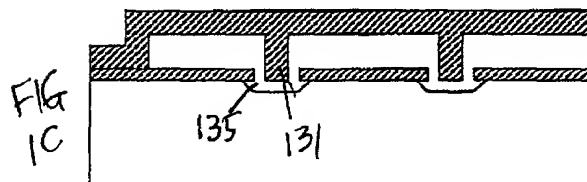


(a) Fabrication of the Parylene structures with "posts"

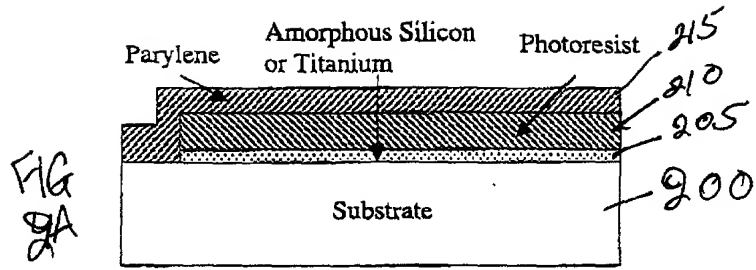


(b) Dissolution of photoresist in acetone

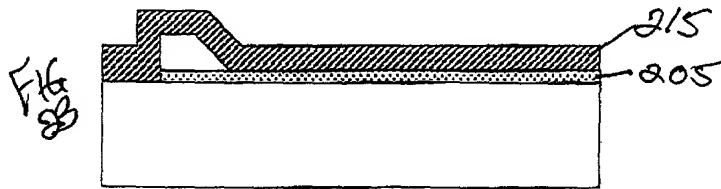


(c) Free the structures with gas phase silicon etching

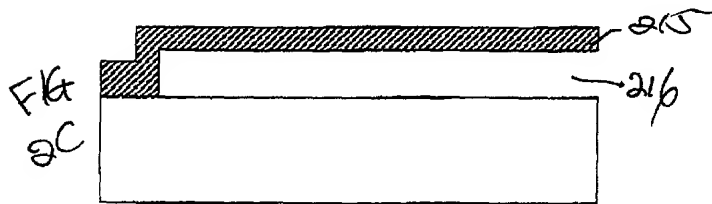
Figure 3 Anti-stiction technology with "posts"



(a) Fabrication of the Parylene structures with composite sacrificial layer

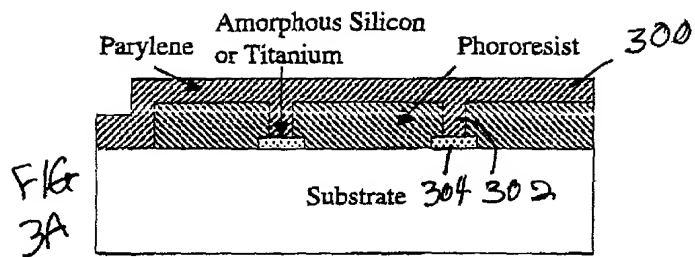


(b) Dissolution of photoresist in acetone

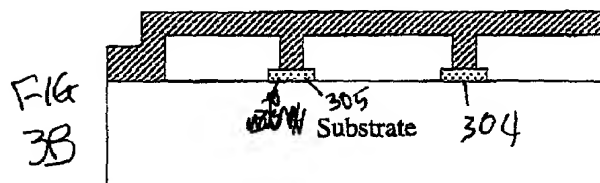


(c) Free the structures with gas phase etching

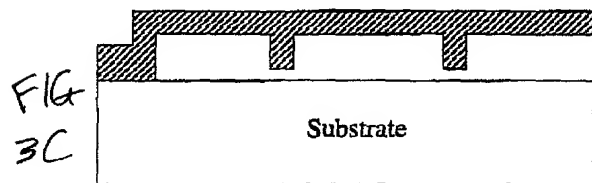
Figure 4 Anti-stiction technology with composite sacrificial layer



(a) Fabrication of the Parylene structures with "posts"



(b) Dissolution of photoresist in acetone



(c) Free the structures with gas phase etching

Figure 3 Anti-stiction technology with "posts" and composite sacrificial layer